Supplementary Material

Investigation of the dual-parameter material removal framework for coordinated multi-TlFs planning in magnetorheological jet polishing

Yulu Miao[1], Yunpeng Feng[1] (✉), Haobo Cheng[2] (✉), Kangju Lin[1], Yang Zhang[1], Jiang Wu[1], Kun Gao[1]

1 School of Optics and Photonics, Beijing Institute of Technology, Beijing 100086, China

2 Shenzhen Research Institute, Beijing Institute of Technology, Shenzhen 518507, China

Corresponding author

Emails: roc@bit.edu.cn (Y. Feng); chb@bit.edu.cn (H. Cheng)

List of abbreviations

B-TIF	Bevel-cut-like tool influence function
CCOS	Computer-controlled optical surfacing
CeO_2	Cerium oxide
CFD	Computational fluid dynamics
CIP	Carbonyl iron powder
DPM	Discrete phase model
EAF	Edge amplification factor
FWHM	Full width at half maximum
LCI	Local coupling index
MJP	Magnetorheological jet polishing
MLA	Microlens array
MR	Magnetorheological
MRF	Magnetorheological finishing
NJP	Nanoparticle jet polishing
NNHD	Nearest neighbor height difference
PV	Peak-to-valley
SST	Shear stress transport
TIF	Tool influence function
VOF	Volume of fluid